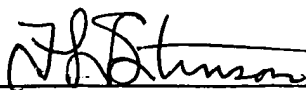


INFORMATION DISCLOSURE STATEMENT BY APPLICANT Form PTO-1449 (Modified) (Use several sheets if necessary)				COMPLETE IF KNOWN	
				Application Number	Not Yet Assigned
				Confirmation Number	
				Filing Date	November 25, 2003
				First Named Inventor	Eric J. BERGMAN
				Group Art Unit	
Examiner Name					
Sheet	1	of	3	Attorney Docket No.	54008.8100.US01 (P01-0015US2)

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
JHS	AA	4,186,032		Ham	01/29/80	
	AB	4,749,440		Blackwood et al.	06/07/88	
	AC	4,817,652		Liu	04/04/89	
	AD	4,917,123		McConnell et al.	04/17/90	
	AE	4,974,530		Lyon	12/04/90	
	AF	5,032,218		Dobson	07/16/91	
	AG	5,055,138		Slinn	10/08/91	
	AH	5,063,609		Lorimer	11/05/91	
	AI	5,071,485		Matthews et al.	12/10/91	
	AJ	5,105,556		Kurokawa et al.	04/21/92	
	AK	5,120,370		Mori et al.	06/09/92	
	AL	5,160,378		Tuunanen	11/03/92	
	AM	5,181,985		Lampert et al.	01/26/93	
	AN	5,232,511		Bergman	08/03/93	
	AO	5,232,870		Ito et al.	08/03/93	
	AP	5,234,540		Grant et al.	08/10/93	
	AQ	5,235,995		Bergman et al.	08/17/93	
	AR	5,244,000		Stanford et al.	09/14/93	
	AS	5,246,526		Yamaguchi et al.	09/21/93	
	AT	5,248,380		Tanaka	09/28/93	
	AU	5,308,745		Schwartzkopf	05/03/94	
	AV	5,326,406		Kaneko et al.	07/05/94	
	AW	5,366,757		Lin	11/22/94	
	AX	5,372,651		Kodama	12/13/94	
	AY	5,378,317		Kashiwase et al.	01/03/95	
	AZ	5,415,191		Mashimo et al.	05/16/95	
	BA	5,447,640		Orni	09/05/95	
	BB	5,464,480		Matthews	11/07/95	
	BC	5,503,708		Koizumi et al.	04/02/96	
	BD	5,520,744		Fujikawa et al.	05/28/96	
	BE	5,571,367		Nakajima et al.	11/05/96	
	BF	5,626,769		Sawamoto	05/06/97	
	BG	5,632,847		Ohno et al.	05/27/97	
	BH	5,647,386		Kaiser	07/15/97	
	BI	5,658,615		Hasebe et al.	08/19/97	
	BJ	5,705,089		Sugihara et al.	01/06/98	
	BK	5,706,842		Caimi et al.	01/13/98	
JHS	BL	5,714,203		Schellenberger et al.	02/03/98	

EXAMINER 	DATE CONSIDERED 12/10/05
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JHS	BM	5,730,806		Caimi et al.	03/24/98	
	BN	5,749,975		Li et al.	05/12/98	
	BO	5,762,755		McNeilly et al.	06/09/98	
	BP	5,776,296		Matthews	07/07/98	
	BQ	5,803,982		Kosofsky et al.	09/08/98	
	BR	5,810,940		Fukazawa	09/22/98	
	BS	5,832,177		Shingawa	11/03/98	
	BT	5,845,662		Sumnitsch	12/08/98	
	BU	5,858,107		Chao et al.	01/12/99	
	BV	5,896,875		Yoneda	04/27/99	
	BW	5,911,837		Matthews	06/15/99	
	BX	5,916,366		Ueyama et al.	06/29/99	
	BY	5,944,907		Ohmi	08/31/99	
	BZ	5,950,643		Miyazaki et al.	09/14/99	
	CA	5,964,952		Kunze-Concewitz	10/12/99	
	CB	5,964,954		Matsukawa et al.	10/12/99	
	CC	5,971,368		Nelson et al.	10/26/99	
	CD	6,030,932		Leon et al.	02/29/00	
	CE	6,146,469		Toshima	11/14/00	
	CF	6,249,933		Berfield	06/26/01	
	CG	6,267,125		Bergman et al.	07/31/01	
	CH	6,273,108		Bergman et al.	08/14/01	
JHS	CI	6,299,696		Kamikawa et al.	10/09/01	

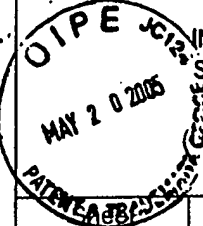
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Examiner Initials*	Cite No.	Foreign Patent or Application			Name of Patentee or Applicant of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Office	NUMBER	Kind Code (if known)				
JHS	CJ	JP	52-012063		Hiroshi Ikeda	04/04/1977		X
	CK	JP	S61-004232		Yukinobu Tanno et al.	01/10/1986		X
	CL	JP	62-117330		Sanyo Elec. Co., Ltd.	05/28/1987		
	CM	JP	63-110732		NEC Corp.	05/16/1988		
	CN	JP	64-042129		Hitachi Ltd.	02/14/1989		
	CO	EP	0 344 764		Wacker Chemitronic	12/06/1989		
	CP	JP	H01-262627		Nippon Denki, K.K.	10/19/1989		X
	CQ	JP	03-072626		Dainippon Screen Mfg. Co., Ltd.	03/27/1991		X
	CR	JP	H03-208900		Nippon Steel Corp.	09/12/1991		X
JHS	CS	JP	H04-125927		Fujitsu, Ltd.	04/27/1992		X

EXAMINER	<i>JHS</i>	DATE CONSIDERED	12/10/05
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				Application Number	Not Yet Assigned
				Confirmation Number	
				Filing Date	November 25, 2003
				First Named Inventor	Eric J. BERGMAN
				Group Art Unit	
Examiner Name					
Sheet	3	of	3	Attorney Docket No.	54008.8100.US01 (P01-0015US2)

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Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
		NUMBER	Kind Code (if known)					
JAS	CT	JP	H04-298038		Hitachi Cable, Ltd.	10/21/1992		X
	CU	JP	04-302144		Hitachi, Ltd.	10/26/1992		
	CV	JP	04-302145		Hitachi Ltd.	10/26/1992		
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	CY	JP	05-109686		Nippon Steel Corp.	04/30/1993		
	CZ	EP	0 548 596 A2		Chlorine Eng. Corp. Ltd.	06/30/1993		X
	DA	JP	05-259139		Hitachi Ltd.	10/08/1993		
	DB	JP	05-283389		NEC Corp.	10/29/1993		X
	DC	JP	06-204130		Mitsubishi Electric Corp.	07/22/1994		X
	DD	JP	07-159980		Nikon Corp.	06/23/1995		
	DE	JP	08-008222		Sony Corporation	01/12/1996		
	DF	EP	0 702 399		Siemens AG	03/20/1996		
	DG	JP	08-160032		Toshiba Corp.	06/21/1996		
	DH	EP	0 782 177 A2		Texas Instruments Incorporated	07/02/1997		X
	DI	WO	99/52654		Bergman et al.	10/21/1999		X
	DJ	JP	52-100473		Yamanouchi Pharm.	08/23/1977		
	DK	JP	64-008630		Tokyo Electron Ltd.	01/12/1989		
DL	JP	63-016127		Yamaha Motor Co. Ltd.	01/23/1988			
DM	JP	03-041729		Tokyo Electron Ltd.	02/22/1991			
DN	JP	01-192712		Nippon Mining Co. Ltd.	08/02/1989			
OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS								
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.					T	

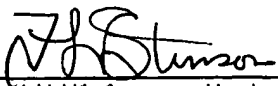
EXAMINER	<i>JAS</i>	DATE CONSIDERED	12/10/05
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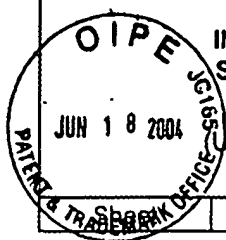
 INFORMATION DISCLOSURE STATEMENT BY APPLICANT Form SB/08A (Use several sheets if necessary)				COMPLETE IF KNOWN	
				Application Number	10/721,495
				Confirmation Number	
				Filing Date	November 25, 2003
				First Named Inventor	Michael Kenny
				Group Art Unit	
				Examiner Name	
1	of	1	Attorney Docket No.	54008.8100.US01 (P01-0015US2)	

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JHS	FA	6,758,938		Torek	08/31/99 F	

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		Office	NUMBER	Kind Code (if known)				
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OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.	T

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Form PTO-1449 (Modified)
Use several sheets if necessary)

COMPLETE IF KNOWN

Application Number	10/721,495
Confirmation Number	
Filing Date	November 25, 2003
First Named Inventor	Michael KENNY
Group Art Unit	
Examiner Name	
Attorney Docket No.	54008.8100.US01 (P01-0015US2)

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U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
JHS	DO	6,551,409		DeGendt	04/22/03	
JHS	DP	2002/0011257		DeGendt	01/31/02	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.	Foreign Patent or Application			Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
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JHS	DQ	Alder, M., <i>et al.</i> , "The Kinetics and Mechanism of Hydroxide Ion Catalyzed Ozone Decomposition in Aqueous Solution." <i>J. Am. Chem. Soc.</i> , 72:1884-1886 (1950).	
	DR	Amick, J.A., "Cleanliness and the Cleaning of Silicon Wafers." <i>Solid State Technology</i> , pp. 47-52 (Nov. 1976).	
	DS	Anantharaman, <i>et al.</i> , "ORGANICS: Detection and Characterization of Organics in Semiconductor DI Water Processes." <i>Ultrapure Water</i> , pp. 30-36 (Apr. 1994).	
	DT	Baumgärtner, H., <i>et al.</i> , "Ozone Cleaning of the Si-SiO ₂ System." <i>Appl. Phys. A</i> , 43:223-226 (1987).	
	DU	Bedge, S., <i>et al.</i> , "Kinetics of UV/O ₂ Cleaning and Surface Passivation: Experiments and Modeling." <i>Mat. Res. Soc. Symp. Proc.</i> , 259:207-212 (1992).	
	DV	Bolon, D.A., <i>et al.</i> , "Ultraviolet Depolymerization of Photoresist Polymers," <i>Polymer Engineering and Science</i> , 12(2):108-111 (March 1972)	
JHS	DW	Christenson, K., <i>et al.</i> , "Deionized Water Helps Remove Wafer Stripping 'Resist'-ance." www.precisioncleaningweb.com -- <i>Precision Cleaning Web--Archives</i> , pp. 10-20 (Apr. 1998).	

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DATE CONSIDERED


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[54008.8100.US01/LA041610.019]

INFORMATION DISCLOSURE STATEMENT BY APPLICANT Form PTO-1449 (Modified) (Use several sheets if necessary)				COMPLETE IF KNOWN	
				Application Number	10/721,495
				Confirmation Number	
				Filing Date	November 25, 2003
				First Named Inventor	Michael KENNY
				Group Art Unit	
Examiner Name					
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OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS			
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JPS	DX	Egitto, F.D., <i>et al.</i> , "Removal of Poly (Dimethylsiloxane) Contamination From Silicon Surfaces With UV/Ozone Treatment." <i>Mat. Res. Soc. Symp. Proc.</i> , 385:245-250 (1995).	
	DY	Gabriel, C., <i>et al.</i> , "Reduced Device Damage Using An Ozone Based Photoresist Removal Process." <i>SPIE Advances in Resist Technology and Processing VI</i> , 1086:598-604 (1989).	
	DZ	Ganesan, G., <i>et al.</i> , "Characterizing Organic Contamination in IC Package Assembly." <i>The Int'l. Soc. for Hybrid Microelectronics</i> , 17(2), Second Quarter, 152-160 (1994).	
	EA	Golland, D.E., <i>et al.</i> , "The Clean Module: Advanced Technology for Processing Silicon Wafers." <i>Semiconductor Int'l.</i> , pp. 154-157 (Sep. 1987).	
	EB	Goulding, M.R., "The selective epitaxial growth of silicon," <i>Materials Science and Engineering</i> , Vol. B17, pp. 47-67 (1993).	
	EC	Heyns, M.M., <i>et al.</i> , "New Wet Cleaning Strategies for Obtaining Highly Reliable Thin Oxides." <i>MRP Symposium Proceedings on Materials Research Society</i> , Spring Meeting, San Francisco, CA, Apr. 12-13, p. 35 (1993).	
	ED	Huynh, C., <i>et al.</i> , "Plasma versus ozone photoresist ashing: Temperature effects on process-induced mobile ion contamination." <i>J. Vac. Sci. Technol.</i> , B9(2):353-356 (Mar./Apr. 1991).	
	EE	Isagawa, T., <i>et al.</i> , "Ultra Clean Surface Preparation Using Ozonized Ultrapure Water." <i>Extended Abstracts of the 1992 Int'l. Conf. on Solid State Devices and Materials</i> , pp. 193-195 (1992).	
	EF	Kasi, S., <i>et al.</i> , "Surface Hydrocarbon Removal from Si by UV/Ozone." <i>ECS Extended Abstracts</i> , No. 458, pp. 691-692 (1990).	
	EG	Kasi, S., <i>et al.</i> , "Vapor phase hydrocarbon removal for Si processing." <i>Appl. Phys. Lett.</i> , 57(20):2095-2097 (Nov. 1990).	
JPS	EH	Kern, W., "The Evolution of Silicon Wafer Cleaning Technology." <i>J. Electrochem. Soc.</i> , 137(6):1887-1892 (Jun. 1990).	

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				Filing Date	November 25, 2003
				First Named Inventor	Michael KENNY
				Group Art Unit	
Examiner Name					
Sheet	3	of	4	Attorney Docket No.	54008.8100.US01 (P01-0015US2)


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JBS	EI	Krusell, W.C., et al., "Cleaning Technologies for High Volume Production of Silicon Wafers." <i>ECS Proc. of the First Int'l. Symposium on Cleaning Technology in Semiconductor Device Mfg.</i> , pp. 23-32 (Oct. 1989).		
	EJ	Krusell, W.C., et al., "The Characterization of Silicon Substrate Cleaning Treatments by use of SIMS and MOS Electrical Testing." <i>ECS Extended Abstracts</i> , No. 229, p. 331-332 (1986).		
	EK	Nelson, S., "Ozonated water for photoresist removal." <i>Solid State Technology</i> , p. 107-112 (Jul. 1999).		
	EL	Ohmi, T., et al., "Native Oxide Growth and Organic Impurity Removal on Si Surface with Ozone-Injected Ultrapure Water." <i>J. Electrochem. Soc.</i> , 140(3):804-810 (Mar. 1993).		
	EM	Sehested, K., et al., "Decomposition of Ozone in Aqueous Acetic Acid Solutions (pH 0-4)." <i>J. Phys. Chem.</i> , pp. 1005-1009 (1992).		
	EN	Shimada, H., et al., "Residual-Surfactant-Free Photoresist Development Process." <i>J. Electrochem., Soc.</i> , 139(6):1721-1730 (Jun. 1992).		
	EO	Suemitsu, M., et al., "Low Temperature Silicon Surface Cleaning by HF Etching/Ultraviolet Ozone Cleaning (HF/UVOC) Method (I)-Optimization of the HF Treatment." <i>Japanese Journal of Applied Physics</i> , 28(12):2421-2424 (Dec. 1989).		
	EP	Tabbe, M., "UV ozone cleaning of silicon substrates in silicon molecular beam epitaxy." <i>Appl. Phys. Lett.</i> , 45(10):1073-1075 (Nov. 1984).		
	EQ	Tong, J., et al., "Aqueous Ozone Cleaning of Silicon Wafers." <i>ECS Extended Abstracts</i> , Phoenix, AZ, Abstract No. 506, pp. 753 (Oct. 13-17, 1991).		
	ER	Tong, J., et al., "Aqueous Ozone Cleaning of Silicon Wafers." <i>Proc. of 2.sup.nd Int'l. Symposium on Cleaning Tech. In Semiconductor Device Mfg.</i> , pp. 18-25 (Oct. 1992).		
	ES	Vig, J., "UV/Ozone Cleaning of Surfaces." <i>U.S. Army Elec. Tech. and Devices Lab.</i> , pp. 1-26.		
JBS	ET	Vig, J., "UV/Ozone Cleaning of Surfaces: A Review." <i>Surface Contamination: Genesis, Detection, and Control</i> , pp. 235-253 (1979).		

EXAMINER	DATE CONSIDERED
JBS	12/10/05
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				Application Number	10/721,495
				Confirmation Number	
				Filing Date	November 25, 2003
				First Named Inventor	Michael KENNY
				Group Art Unit	
Examiner Name					
Sheet	4	of	4	Attorney Docket No.	54008.8100.US01 (P01-0015US2)

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JPS	EU	Vig, J., et al., "UV/Ozone Cleaning of Surfaces." <i>IEEE Transactions on Parts, Hybrids, and Packaging</i> , Vol. PHP-12(4):365-370 (Dec. 1976).	
	EV	Vig, J., "UV/Ozone Cleaning of Surfaces." <i>U.S. Army Electronics Technology and Devices Laboratory</i> , ERADCOM, Ft. Monmouth, NJ, 07703-5302, pp. 1027-1034 (Sep./Oct. 1984).	
	EW	Zafonte, L., et al., "UV/Ozone Cleaning For Organics Removal on Silicon Wafers." <i>SPIE Optical Microlithography III: Technology for the Next Decade</i> , 470:164-175 (1984).	
	EX	Zazzera, L.A., et al., "XPS and SIMS Study of Anhydrous HF and UV/Ozone-Modified Silicon (100) Surfaces." <i>J. Electrochem. Soc.</i> , 136(2):484-491 (Feb. 1989).	
	EY	"Ozone Concentration Measurement in a Process Gas." <i>Proposed IOA Pan American Group Guideline</i> , pp. 1-21 (Dec. 1993).	
JPS	EZ	"Ozone for Semiconductor Applications." <i>Sorbios</i> , pp. 1-6 (Oct. 1991).	

EXAMINER JH Stinson	DATE CONSIDERED 12/10/05
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT Form SB/08A (Use several sheets if necessary)				COMPLETE IF KNOWN	
				Application Number	10/721,495
				Confirmation Number	6048
				Filing Date	November 25, 2003
				First Named Inventor	Michael Kenny
				Group Art Unit	1746
				Examiner Name	Frankie L. Stinson
Sheet	1	of	4	Attorney Docket No.	54008.8100.US01 (P05-0015US2)

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Examiner Initials*	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Inventor of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
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				Application Number	10/721,495
				Confirmation Number	6048
				Filing Date	November 25, 2003
				First Named Inventor	Michael Kenny
				Group Art Unit	1746
				Examiner Name	Frankie L. Stinson
Sheet	2	of	4	Attorney Docket No.	54008.8100.US01 (P05-0015US2)

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				Filing Date	November 25, 2003
				First Named Inventor	Michael Kenny
				Group Art Unit	1746
				Examiner Name	Frankie L. Stinson
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